

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Tetsuo SHIMOMURA et al.  
App. No : 10/598,717  
Filed : September 8, 2006  
For : POLISHING PAD AND  
SEMICONDUCTOR DEVICE  
MANUFACTURING METHOD  
Examiner : Alvin J. Grant  
Art Unit : 3723  
Conf No. : 9262

AMENDMENT ACCOMPANYING RCE**Mail Stop RCE**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed November 12, 2008, please reconsider the present application in light of the following amendments and comments

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 8 of this paper.